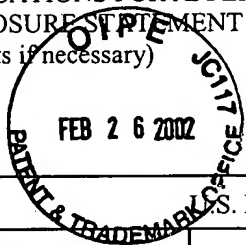
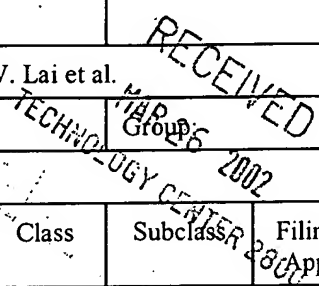

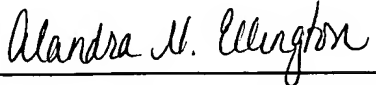


Form PTO-1449 (Modified) Page 1 of 1 LIST OF PATENTS AND PUBLICATIONS FOR APPLICANT'S INFORMATION DISCLOSURE STATEMENT (Use several sheets if necessary)				Atty. Docket No.: 530.011		Serial No.: 10/045,438	
				Applicant: Jonathan W. Lai et al.			
				Filing Date: 11/07/01			
REFERENCE DESIGNATION U.S. PATENT DOCUMENTS							
Examiner Initial		Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate
	AA						
	AB						
	AC						
	AD						
	AE						
	AF						
	AG						
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	AL						
	AM						
	AN						
	AO						
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	AQ						
	AR						
	AS						
	AT						
FOREIGN PATENT DOCUMENTS							
		Document Number	Date	Country	Class	Subclass	Translation
							Yes No
	AU						
OTHER ART (Including Author, Title, Date, Pertinent Pages, Etc.)							
	AV	Article entitled "A New Technique For Producing Large-Area As-Deposited Zero-Stress LPCVD Polysilicon Films: The <i>MultiPoly</i> Process," by Jie Yang et al., from IEEE Journal of Microelectronmechanical Systems, Vol. 9, No. 4, December 2000.					
EXAMINER 				DATE CONSIDERED 11/15/03			
EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.							